

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoru Okamoto Art Unit : 1792
Serial No. : 10/689,617 Examiner : Mahmoud Dahimene
Filed : October 22, 2003 Conf. No. : 4799
Title : METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD
FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING
SEMICONDUCTOR DEVICE

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

NOTICE OF APPEAL

Applicant hereby appeals to the Board of Patent Appeals and Interferences from the action dated November 13, 2007, finally rejecting claims 1-84.

The fee in the amount of \$510 for the appeal fee is being paid concurrently herewith on the Electronic Filing System (EFS) by way of Deposit Account authorization. Please apply any other charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 2/13/08

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